

00862.022239

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Shigeyuki UZAWA et al.) : Examiner: R. A. Jarrett
Application No.: 09/864,309) : Group Art Unit: 2125
Filed: May 25, 2001) : Confirmation No.: 2803
For: EXPOSURE APPARATUS, COATING/DEVELOPING)
SYSTEM, DEVICE MANUFACTURING SYSTEM, : October 10, 2006
DEVICE MANUFACTURING METHOD,) (Tuesday after Federal
SEMICONDUCTOR MANUFACTURING FACTORY, : Holiday)
AND EXPOSURE APPARATUS MAINTENANCE)
METHOD :
:

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

PRELIMINARY AMENDMENT

Sir:

Prior to further examination on the merits, please amend the above-identified application as follows: